

**AMENDMENTS TO THE CLAIMS**

Please amend the claims as follows:

1. (Currently Amended) A vacuum deposition apparatus comprising:

a susceptor for heating a glass substrate, a portion of the susceptor providing an area used as a sliding portion on which to slide the glass substrate to a ~~desired~~ stopped position;

lift pins for supporting the glass substrate;

a robot arm for transferring the glass substrate onto the susceptor and returning the glass substrate from the susceptor, wherein the robot arm supports a portion of the glass substrate with a non-supported edge portion freely hanging over the robot arm such that as the robot arm moves in a forward direction to transfer the glass substrate onto the susceptor, the non-supported edge portion of the glass substrate slides the glass substrate on the sliding portion of the susceptor and is stopped by at least one stopping pin located at the stopping position; and

a groove formed in said sliding portion of the susceptor at a location of the at least one stopping pin for receiving material resulting from sliding of the glass substrate ~~by the robot arm on the surface~~ on the sliding portion of the susceptor.

2. (Canceled)

3. (Currently Amended) The vacuum deposition apparatus according to claim 21, wherein a length of said sliding portion, measured from said groove, is 10 mm.

4. (Previously Presented) The vacuum deposition apparatus according to claim 1, wherein the susceptor is made of a quartz material.

5. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the ~~section of said groove formed in said portion of the susceptor~~ has a polygonal configuration.

6. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein ~~the~~ a bottom face of the groove ~~formed in said portion of the susceptor~~ has a curved configuration.

7. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein ~~the~~ a bottom face of the groove ~~formed in said portion of the susceptor~~ includes an incline plane and a perpendicular plane.

8. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the groove ~~formed in said portion of the susceptor~~ has a V-shaped configuration.

9. (Canceled)

10. (Previously Presented) The vacuum deposition apparatus according to claim 4, wherein the susceptor is in direct contact with the glass substrate when the glass substrate is heated.

11. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the ~~robot arm~~non-supported portion of the glass substrate inclines ~~the glass substrate~~ with respect to a surface of the sliding portion of the susceptor when ~~sliding the glass substrate is~~ slid along the sliding portion of the susceptor.

12. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the ~~sliding portion of the~~ susceptor comprises:

a first planar portion;

a second planar portion vertically above the first planar portion and horizontally contiguous with the first planar portion such that the first and second planar portions of the susceptor form a stepped-shape,

wherein the groove is formed in the second planar portion, and

wherein the glass substrate slides on the second planar portion.

13-14. (Canceled)

15. (Currently Amended) The vacuum deposition apparatus according to claim 11, wherein ~~the robot arm is configured to~~ the incline of the non-supported edge of the glass substrate ~~at~~ is substantially ~~at~~ 85 degrees from a vertical when sliding the glass substrate on the sliding portion of the susceptor.

16. (Previously Presented) The vacuum deposition apparatus according to claim 1, wherein the susceptor is rectangular.